

CAU 1765

AMENDMENT TRANSMITTAL LETTER (Large Entity)

Applicant(s): Kei-Yu Ko

Docket No.

11675.114

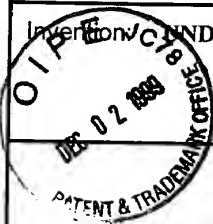
Serial No.
08/846,671

Filing Date
April 30, 1997

Examiner
Goudreau

Group Art Unit
1765

Inventor(s): UNDOPED SILICON DIOXIDE AS ETCH STOP FOR SELECTIVE ETCH OF DOPED SILICON DIOXIDE



TO THE ASSISTANT COMMISSIONER FOR PATENTS:

Transmitted herewith is an amendment in the above-identified application.

The fee has been calculated and is transmitted as shown below.

CLAIMS AS AMENDED

	CLAIMS REMAINING AFTER AMENDMENT	HIGHEST # PREV. PAID FOR	NUMBER EXTRA CLAIMS PRESENT	RATE	ADDITIONAL FEE
TOTAL CLAIMS	51 -	54 =	0 x	\$18.00	\$0.00
INDEP. CLAIMS	7 -	8 =	0 x	\$78.00	\$0.00
Multiple Dependent Claims (check if applicable) <input type="checkbox"/>					\$0.00
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT					\$0.00

- ☒ No additional fee is required for amendment.
- ☐ Please charge Deposit Account No. _____ in the amount of _____
A duplicate copy of this sheet is enclosed.
- ☐ A check in the amount of _____ to cover the filing fee is enclosed.
- ☒ The Commissioner is hereby authorized to charge payment of the following fees associated with this communication or credit any overpayment to Deposit Account No. 23-3178
A duplicate copy of this sheet is enclosed.
- ☒ Any additional filing fees required under 37 C.F.R. 1.16.
- ☒ Any patent application processing fees under 37 CFR 1.17.

Signature

Dated: November 24, 1999

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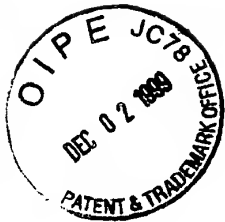
I certify that this document and fee is being deposited on Nov. 24, 1999 with the U.S. Postal Service as first class mail under 37 C.F.R. 1.8 and is addressed to the Assistant Commissioner for Patents, Washington, D.C. 20231.

Signature of Person Mailing Correspondence

Peggy R. Huft

Typed or Printed Name of Person Mailing Correspondence

CC:



PATENT APPLICATION
Docket No: 11675.114

#5/A
4a
12/8/99

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of:

Kei-Yu Ko

Serial No.: 08/846,671

Filed: April 30, 1997

**For: UNDOPED SILICON DIOXIDE AS
 ETCH STOP FOR SELECTIVE ETCH
 OF DOPED SILICON DIOXIDE**

Examiner: George A. Goudreau

Unit 176

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**AMENDMENT "A" AND ELECTION IN RESPONSE TO
RESTRICTION REQUIREMENT**

Honorable Commissioner of Patents
and Trademarks
Washington, D.C. 20231

Sir:

IN THE CLAIMS:

Please cancel Claims 47-49 without prejudice to the filing of a divisional patent application.